Jianmin Miao

List of Publications by Year
in descending order

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237	6,685	53660	74018
papers	citations	45 h-index	75 g-index

240	240	240	7183
all docs	docs citations	times ranked	citing authors

#	Article	IF	Citations
1	Harbor seal whisker inspired self-powered piezoelectric sensor for detecting the underwater flow angle of attack and velocity. Measurement: Journal of the International Measurement Confederation, 2021, 172, 108866.	2.5	15
2	A new sensor inspired by the lateral-line system of fish using the self-powered d33 mode piezoelectric diaphragm for hydrodynamic sensing. Mechanical Systems and Signal Processing, 2020, 141, 106476.	4.4	19
3	Investigation of a Thinâ€film Quasiâ€reference Electrode Fabricated by Combined Sputteringâ€evaporation Approach. Electroanalysis, 2019, 31, 560-566.	1.5	9
4	PVDF Nanofiber Sensor for Vibration Measurement in a String. Sensors, 2019, 19, 3739.	2.1	27
5	Ka -Band Symmetric V-Shaped Meander-Line Slow Wave Structure. IEEE Transactions on Plasma Science, 2019, 47, 4650-4657.	0.6	27
6	An intrinsically stretchable humidity sensor based on anti-drying, self-healing and transparent organohydrogels. Materials Horizons, 2019, 6, 595-603.	6.4	297
7	Highlighting the uniqueness in dielectrophoretic enrichment of circulating tumor cells. Electrophoresis, 2019, 40, 1457-1477.	1.3	23
8	A flyover style microfluidic chip for highly purified magnetic cell separation. Biosensors and Bioelectronics, 2019, 129, 175-181.	5.3	54
9	Gravity-Independent Oscillate Boiling. Microgravity Science and Technology, 2019, 31, 767-773.	0.7	2
10	A New Self-Powered Sensor Using the Radial Field Piezoelectric Diaphragm in d33 Mode for Detecting Underwater Disturbances. Sensors, 2019, 19, 962.	2.1	13
11	MEMS/NEMS-Enabled Energy Harvesters as Self-Powered Sensors. SpringerBriefs in Applied Sciences and Technology, 2019, , 1-30.	0.2	5
12	Ultrastretchable and Stable Strain Sensors Based on Antifreezing and Self-Healing Ionic Organohydrogels for Human Motion Monitoring. ACS Applied Materials & Interfaces, 2019, 11, 9405-9414.	4.0	285
13	Self-Steerable Propulsion of Disk-Like Micro-Craft with Dual Off-Center Nanoengines. ACS Applied Energy Materials, 2019, 2, 1657-1662.	2.5	5
14	Extremely Deformable, Transparent, and High-Performance Gas Sensor Based on Ionic Conductive Hydrogel. ACS Applied Materials & Interfaces, 2019, 11, 2364-2373.	4.0	180
15	In-phase synchronization between two auto-oscillating bubbles. Physical Review Fluids, 2019, 4, .	1.0	6
16	Diffraction grating integrated on micromachined stepper motor for diversity implementation in imaging spectroscopy. , 2018, , .		2
17	On-Wafer Microstrip Meander-Line Slow-Wave Structure at Ka-Band. IEEE Transactions on Electron Devices, 2018, 65, 2142-2148.	1.6	35
18	3D superhydrophobic reduced graphene oxide for activated NO₂ sensing with enhanced immunity to humidity. Journal of Materials Chemistry A, 2018, 6, 478-488.	5.2	116

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19	Optimized Polyvinylidene Fluoride Nanofiber Webs for Flexible Energy Harvesters. Proceedings (mdpi), 2018, 2, .	0.2	1
20	Flexible Graphitized Polyacrylonitrile Nanofiber Bundles for Strain Sensors. , 2018, , .		3
21	Hydrogel-CNT Biomimetic Cilia for Flow Sensing. , 2018, , .		2
22	In-plane Rotational Tuning of Polymer Diffraction Grating for Diverse Imaging Spectroscopy. , 2018, , .		1
23	Nanoparticles-Modified Chemical Sensor Fabricated on a Flexible Polymer Substrate for Cadmium(II) Detection. Polymers, 2018, 10, 694.	2.0	7
24	Oscillate Boiling from Electrical Microheaters. Physical Review Applied, 2018, 10, .	1.5	14
25	Wafer-Level Integration of Replicated Polymer Micro-Optics With Micromechanical Systems. IEEE Photonics Technology Letters, 2018, 30, 2017-2020.	1.3	1
26	Characterization on Threeâ€Dimensional Trajectory of Diskâ€Like Goldâ€Nickelâ€Platinum Nanomotor Using Digital Holographic Imaging. ChemistrySelect, 2018, 3, 9634-9640.	0.7	4
27	Three-dimensional hierarchical and superhydrophobic graphene gas sensor with good immunity to humidity. , 2018, , .		4
28	Highly Stretchable and Transparent Thermistor Based on Self-Healing Double Network Hydrogel. ACS Applied Materials & Interfaces, 2018, 10, 19097-19105.	4.0	168
29	Engineering biomimetic hair bundle sensors for underwater sensing applications. AIP Conference Proceedings, 2018, , .	0.3	7
30	Water Hardness Determination Using Disposable MEMS-Based Electrochemical Sensor. , 2018, , .		2
31	Design and Fabrication of a Stretchable Circuit Board for Wireless Posture Measurement. IEEE Electron Device Letters, 2017, 38, 399-402.	2.2	6
32	Enhanced electrostatic vibrational energy harvesting using integrated opposite-charged electrets. Journal of Micromechanics and Microengineering, 2017, 27, 044002.	1.5	47
33	MEMS/NEMS-Enabled Vibrational Energy Harvesting for Self-Powered and Wearable Electronics. , 2017, , 271-297.		1
34	Sub-wavelength optical lithography via nanoscale polymer lens array. , 2017, , .		1
35	3D sulfonated graphene hydrogel for enhanced chemical sensing. , 2017, , .		1
36	Polymer MEMS sensor for flow monitoring in biomedical device applications. , 2017, , .		3

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37	Flexible liquid crystal polymer-based electrochemical sensor for in-situ detection of zinc(II) in seawater. Mikrochimica Acta, 2017, 184, 3007-3015.	2.5	23
38	Fabrication and performance characterization of miniature axial fans. Microsystem Technologies, 2017, 23, 5717-5725.	1.2	1
39	Hemispherical array of sensors with contractively wrapped polymer petals for flow sensing. Smart Materials and Structures, 2017, 26, 115008.	1.8	3
40	Microfabricated thin-film reference electrode for disposable electrochemical sensors. , 2017, , .		0
41	Biomimetic hydrogel-CNT network induced enhancement of fluid-structure interactions for ultrasensitive nanosensors. NPG Asia Materials, 2017, 9, e440-e440.	3.8	22
42	Gradient lithography using graded tip array. , 2017, , .		0
43	Superior gas detection by nanoporous graphene structures. , 2017, , .		0
44	Electrospun polyvinylidene fluoride nanofiber mats for self-powered sensors. , 2017, , .		5
45	Crocodile-inspired dome shaped sensors for underwater object detection. , 2017, , .		1
46	Flexible Hydrogel Capacitive Pressure Sensor for Underwater Applications. Proceedings (mdpi), 2017, 1, .	0.2	6
47	Cupula-Inspired Hyaluronic Acid-Based Hydrogel Encapsulation to Form Biomimetic MEMS Flow Sensors. Sensors, 2017, 17, 1728.	2.1	25
48	MEMS Tunable Diffraction Grating for Spaceborne Imaging Spectroscopic Applications. Sensors, 2017, 17, 2372.	2.1	13
49	Nanofibril scaffold assisted MEMS artificial hydrogel neuromasts for enhanced sensitivity flow sensing. Scientific Reports, 2016, 6, 19336.	1.6	80
50	MEMS artificial neuromast arrays for hydrodynamic control of soft-robots. , 2016, , .		4
51	Biomimetic flow sensors for biomedical flow sensing in intravenous tubes. , 2016, , .		2
52	Chemically functionalized 3D graphene hydrogel for high performance gas sensing. Journal of Materials Chemistry A, 2016, 4, 8130-8140.	5.2	106
53	Miniaturized chemical sensor with bio-inspired micropillar working electrode array for lead detection. Sensors and Actuators B: Chemical, 2016, 233, 249-256.	4.0	23
54	Design of a Sheet-Beam Electron-Optical System for a Microfabricated <inline-formula> <tex-math notation="LaTeX">W </tex-math> </inline-formula>-Band Traveling-Wave Tube Using a Cold Cathode. IEEE Transactions on Electron Devices, 2016, 63, 3725-3732.	1.6	15

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55	Development of a MEMSâ€based electrochemical aptasensor for norovirus detection. Micro and Nano Letters, 2016, 11, 582-585.	0.6	24
56	Crocodile-inspired dome-shaped pressure receptors for passive hydrodynamic sensing. Bioinspiration and Biomimetics, 2016, 11, 056007.	1.5	24
57	Facile Synthesis of 3D Graphene Flowers for Ultrasensitive and Highly Reversible Gas Sensing. Advanced Functional Materials, 2016, 26, 7462-7469.	7.8	149
58	From Biological Cilia to Artificial Flow Sensors: Biomimetic Soft Polymer Nanosensors with High Sensing Performance. Scientific Reports, 2016, 6, 32955.	1.6	117
59	Fully integrated electromagnetic actuator using resin-bonded NdFeB micromagnets. , 2016, , .		0
60	Hydrogen-peroxide-fuelled platinumâ€“nickelâ€“SU-8 microrocket with steerable propulsion using an eccentric nanoengine. RSC Advances, 2016, 6, 102513-102518.	1.7	8
61	A Wideband Microfabricated Ka-Band Planar Helix Slow-Wave Structure. IEEE Transactions on Electron Devices, 2016, 63, 2900-2906.	1.6	23
62	Large-Area Sub-Wavelength Optical Patterning via Long-Range Ordered Polymer Lens Array. ACS Applied Materials & Interfaces, 2016, 8, 16368-16378.	4.0	13
63	A novel two-degree-of-freedom MEMS electromagnetic vibration energy harvester. Journal of Micromechanics and Microengineering, 2016, 26, 035020.	1.5	90
64	3D porous graphene hydrogel for improved gas sensing performance at elevated temperature. , 2016, , .		1
65	Disk-like nanojets with steerable trajectory using platinum nozzle nanoengines. RSC Advances, 2016, 6, 3399-3405.	1.7	12
66	Biomimetic Survival Hydrodynamics and Flow Sensing. Annual Review of Fluid Mechanics, 2016, 48, 1-24.	10.8	97
67	MEMS sensors for assessing flow-related control of an underwater biomimetic robotic stingray. Bioinspiration and Biomimetics, 2015, 10, 036008.	1.5	45
68	Sandwich-structured two-dimensional MEMS electret power generator for low-level ambient vibrational energy harvesting. Sensors and Actuators A: Physical, 2015, 228, 95-103.	2.0	49
69	Production of centimeter-scale sub-wavelength nanopatterns by controlling the light path of adhesive photomasks. Journal of Materials Chemistry C, 2015, 3, 6796-6808.	2.7	7
70	Soft polymer membrane micro-sensor arrays inspired by the mechanosensory lateral line on the blind cavefish. Journal of Intelligent Material Systems and Structures, 2015, 26, 38-46.	1.4	43
71	Artificial fish skin of self-powered micro-electromechanical systems hair cells for sensing hydrodynamic flow phenomena. Journal of the Royal Society Interface, 2015, 12, 20150322.	1.5	113
72	Spiral electrode d33 mode piezoelectric diaphragm combined with proof mass as energy harvester. Journal of Micromechanics and Microengineering, 2015, 25, 035004.	1.5	8

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73	Enhanced Visualization of Fine Needles Under Sonographic Guidance Using a MEMS Actuator. Sensors, 2015, 15, 3107-3115.	2.1	8
74	Production of Centimeter-Scale Gradient Patterns by Graded Elastomeric Tip Array. ACS Applied Materials & Interfaces, 2015, 7, 6991-7000.	4.0	10
75	Design and implementation of an out-of-plane electrostatic vibration energy harvester with dual-charged electret plates. Microelectronic Engineering, 2015, 135, 32-37.	1.1	51
76	Improved Selectivity and Sensitivity of Gas Sensing Using a 3D Reduced Graphene Oxide Hydrogel with an Integrated Microheater. ACS Applied Materials & Interfaces, 2015, 7, 27502-27510.	4.0	132
77	Charging and characterization of non-patterned organic micro electret arrays. Journal of Micromechanics and Microengineering, 2014, 24, 085004.	1.5	0
78	A three-dimensional electret-based micro power generator for low-level ambient vibrational energy harvesting. Journal of Micromechanics and Microengineering, 2014, 24, 065022.	1.5	51
79	Touch at a distance sensing: lateral-line inspired MEMS flow sensors. Bioinspiration and Biomimetics, 2014, 9, 046011.	1.5	69
80	MEMS artificial canal neuromast sensor arrays for underwater sensing. , 2014, , .		0
81	Biotin-Streptavidin Binding Interactions of Dielectric Filled Silicon Bulk Acoustic Resonators for Smart Label-Free Biochemical Sensor Applications. Sensors, 2014, 14, 4585-4598.	2.1	7
82	Self-powered micro-sensors to improve control and maneuvering of a robotic stingray. , 2014, , .		1
83	Out-of-plane micro triple-hot-wire anemometer based on Pyrex bubble for airflow sensing. , 2014, , .		4
84	Demonstration abstract: A MEMS-based airflow sensor network. , 2014, , .		0
85	Microstructural investigation of through-silicon via fabrication by pulse-reverse electroplating for high density nanoelectronics. International Journal of Nanotechnology, 2014, 11, 178.	0.1	0
86	Horizontally suspended carbon nanotube bundles patterned on silicon trench sidewalls. International Journal of Nanotechnology, 2014, 11, 222.	0.1	1
87	Horizontally suspended carbon nanotube bundles patterned on silicon trench sidewalls. , 2013, , .		0
88	Flexible and Surface-Mountable Piezoelectric Sensor Arrays for Underwater Sensing in Marine Vehicles. IEEE Sensors Journal, 2013, 13, 3918-3925.	2.4	99
89	Proof mass effects on spiral electrode d<inf>33</inf> mode piezoelectric diaphragm-based energy harvester. , 2013, , .		7
90	Whisker-like geometries and their force reduction properties. , 2013, , .		14

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91	d33 mode piezoelectric diaphragm based acoustic transducer with high sensitivity. Sensors and Actuators A: Physical, 2013, 189, 93-99.	2.0	28
92	Void formation over limiting current density and impurity analysis of TSV fabricated by constant-current pulse-reverse modulation. Microelectronics Reliability, 2013, 53, 1943-1953.	0.9	28
93	Localized synthesis of horizontally suspended carbon nanotubes. Carbon, 2013, 57, 259-266.	5.4	14
94	High Sensitivity, Miniature, Full 2-D Anemometer Based on MEMS Hot-Film Sensors. IEEE Sensors Journal, 2013, 13, 1914-1920.	2.4	50
95	Giant Flexoelectric Polarization in a Micromachined Ferroelectric Diaphragm. Advanced Functional Materials, 2013, 23, 124-132.	7.8	45
96	Through-silicon via fabrication with pulse-reverse electroplating for high density nanoelectronics. , 2013, , .		2
97	Light detection by carbon nanotube circuit with strong intertube conduction. , 2012, , .		0
98	Tunable piezoresistance and noise in gate-all-around nanowire field-effect-transistor. Applied Physics Letters, 2012, 100, 063106.	1.5	13
99	Piezoelctric d<inf>33</inf> mode diaphragm energy harvester for self-powered sensor application. , 2012, , .		0
100	Characterization of von Karman street with seal whisker-like sensor. , 2012, , .		2
101	Growth mechanism of carbon nanotubes: a nano Czochralski model. Nanoscale Research Letters, 2012, 7, 356.	3.1	9
102	Piezoresistive Sensing Performance of Junctionless Nanowire FET. IEEE Electron Device Letters, 2012, 33, 1759-1761.	2.2	16
103	Displacement and resonance behaviors of a piezoelectric diaphragm driven by a double-sided spiral electrode. Smart Materials and Structures, 2012, 21, 055001.	1.8	9
104	Minimum detectable strain improvement in junctionless nanowire FET sensors. , 2012, , .		1
105	A practical guide for the fabrication of microfluidic devices using glass and silicon. Biomicrofluidics, 2012, 6, 16505-1650516.	1.2	281
106	Facile growth of horizontally suspended carbon nanotubes. Materials Letters, 2012, 81, 165-168.	1.3	4
107	Chemical composition and physical features of harbor seal (Phoca Vitulina) vibrissae for underwater sensing application. , 2011, , .		2
108	Gate-All-Around Junctionless Nanowire MOSFET With Improved Low-Frequency Noise Behavior. IEEE Electron Device Letters, 2011, 32, 1752-1754.	2.2	80

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109	Temperature Control of Microheaters for Localized Carbon Nanotube Synthesis. Journal of Nanoscience and Nanotechnology, 2011, 11, 10498-10502.	0.9	0
110	Investigation of Influence of Synthesis Parameters on Length and Purity of the Carbon Nanotubes. Journal of Nanoscience and Nanotechnology, 2011, 11, 10682-10686.	0.9	1
111	Reduction of squeeze-film damping in a wafer-level encapsulated RF MEMS DC shunt switch. Sensors and Actuators A: Physical, 2011, 171, 118-125.	2.0	3
112	Microcantilever sensors with embedded piezoresistive transistor read-out: Design and characterization. Sensors and Actuators A: Physical, 2011, 171, 178-185.	2.0	11
113	Micro-piezoelectric immunoassay chip for simultaneous detection of Hepatitis B virus and Î±-fetoprotein. Sensors and Actuators B: Chemical, 2011, 151, 370-376.	4.0	37
114	Growth of horizontally aligned carbon nanotubes from designated sidewalls of DRIE-etched silicon trench. , 2011, , .		0
115	Growth of horizontally aligned dense carbon nanotubes from trench sidewalls. Nanotechnology, 2011, 22, 265614.	1.3	15
116	Gate-bias-controlled sensitivity and SNR enhancement in a nanowire FET pressure sensor. Journal of Micromechanics and Microengineering, 2011, 21, 105007.	1.5	7
117	Fabrication of piezoelectric MEMS devices-from thin film to bulk PZT wafer. Journal of Electroceramics, 2010, 24, 25-32.	0.8	50
118	Numerical simulations of electrokinetic transport of a particle in a microfluidic confined domain. Proceedings of SPIE, 2010, , .	0.8	0
119	GPTS functionalized carbon nanotubes integrated with PZT sensors for detection of anti-goat IgG. , 2010, , .		0
120	Investigation of the effect of adsorption induced surface stress on the resonant frequency of PZT membrane based biosensors. , 2010, , .		0
121	Response of piezoelectric circular microdiaphragm sensors in higher frequency modes. , 2010, , .		0
122	Mechanical and Microstructural Characterization of Through-Silicon Via Fabricated with Constant Current Pulse-Reverse Modulation. Journal of the Electrochemical Society, 2010, 157, D323.	1.3	5
123	Elastic MEMS probe card based on the PDMS substrate. Journal of Micromechanics and Microengineering, 2010, 20, 055038.	1.5	9
124	Investigation of influence of synthesis parameters on length and purity of the CNTs grown by thermal chemical vapor deposition. , 2010, , .		2
125	Piezotransistor-embedded microcantilever platform for strain sensing applications. , 2010, , .		1
126	Temperature control of microheaters for localized carbon nanotube synthesis. , 2010, , .		0

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127	Modified Åkvor/Starr approach in the mechanical-thermal noise analysis of condenser microphone. Journal of the Acoustical Society of America, 2009, 126, 2301-2305.	0.5	5
128	Self-Polarized Piezoelectric Biosensor Array for Multiple Immunoassys Applications. , 2009, , .		0
129	The sound field analysis of piezoelectric micromachined ultrasound transducer array. , 2009, , .		0
130	Local synthesis of aligned carbon nanotube bundle arrays by using integrated micro-heaters for interconnect applications. Nanotechnology, 2009, 20, 295303.	1.3	17
131	Investigation of Carbon Nanotube Growth on Multimetal Layers for Advanced Interconnect Applications in Microelectronic Devices. Journal of the Electrochemical Society, 2009, 156, K23.	1.3	7
132	Synthesis of regular nano-pitched carbon nanotube array by using nanosphere lithography for interconnect applications. Materials Letters, 2009, 63, 867-869.	1.3	6
133	Enhancement of electrokinetically driven microfluidic Tâ€mixer using frequency modulated electric field and channel geometry effects. Electrophoresis, 2009, 30, 3144-3152.	1.3	45
134	A wafer-scale encapsulated RF MEMS switch with a stress-reduced corrugated diaphragm. Sensors and Actuators A: Physical, 2009, 151, 237-243.	2.0	19
135	The stress analysis of Si MEMS devices by micro-Raman technique. Thin Solid Films, 2009, 517, 4905-4908.	0.8	13
136	Optimization of sputtered Cr/Au thin film for diaphragm-based MEMS applications. Thin Solid Films, 2009, 517, 4921-4925.	0.8	46
137	Acoustic transducers with a perforated damping backplate based on PZT/silicon wafer bonding technique. Sensors and Actuators A: Physical, 2009, 149, 277-283.	2.0	42
138	Probing Charged Impurities in Suspended Graphene Using Raman Spectroscopy. ACS Nano, 2009, 3, 569-574.	7.3	196
139	Self-assembled ferrofluid lithography: patterning micro and nanostructures by controlling magnetic nanoparticles. Nanotechnology, 2009, 20, 495301.	1.3	24
140	Friction characteristics of the curved sidewall surfaces of a rotary MEMS device in oscillating motion. Journal of Micromechanics and Microengineering, 2009, 19, 065020.	1.5	4
141	Performance Enhancement by Substrate Perforation for a Wafer-Level Encapsulated RF MEMS DC Shunt Switch. , 2009, , .		2
142	Design optimization of condenser microphone: A design of experiment perspective. Journal of the Acoustical Society of America, 2009, 125, 3641-3649.	0.5	3
143	Fabrication of carbon-nanotube enhanced piezoelectric membrane for biosensor application. International Journal of Nanotechnology, 2009, 6, 762.	0.1	3
144	Silicon nanopillars based 3D stacked microchannel heat sinks concept for enhanced heat dissipation applications in MEMS packaging. Sensors and Actuators A: Physical, 2008, 141, 685-694.	2.0	36

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145	On the wet etching of Pyrex glass. Sensors and Actuators A: Physical, 2008, 143, 154-161.	2.0	130
146	Effect of improved wettability of silicon-based materials with electrolyte for void free copper deposition in high aspect ratio through-vias. Thin Solid Films, 2008, 516, 5194-5200.	0.8	8
147	Micromachined ultrasonic transducers and arrays based on piezoelectric thick film. Applied Physics A: Materials Science and Processing, 2008, 91, 107-117.	1.1	41
148	Micro-machined piezoelectric membrane-based immunosensor array. Biosensors and Bioelectronics, 2008, 24, 638-643.	5.3	53
149	Phase transformation in NiTiHf shape memory alloy thin films. Thin Solid Films, 2008, 516, 5393-5396.	0.8	23
150	Fabrication of Si microstructures using focused ion beam implantation and reactive ion etching. Journal of Micromechanics and Microengineering, 2008, 18, 035003.	1.5	38
151	Numerical and Experimental Investigation of Thermomechanical Deformation in High-Aspect-Ratio Electroplated Through-Silicon Vias. Journal of the Electrochemical Society, 2008, 155, H981.	1.3	38
152	Biosensors based on flexural mode piezo-diaphragm. , 2008, , .		5
153	Through-wafer interconnects using carbon nanotubes synthesized by chemical vapor deposition. , 2008, , .		0
154	A MEMS Device for Studying the Friction Behavior of Micromachined Sidewall Surfaces. Journal of Microelectromechanical Systems, 2008, 17, 921-933.	1.7	22
155	Critical electrode size in measurement ofd33coefficient of films via spatial distribution of piezoelectric displacement. Journal Physics D: Applied Physics, 2008, 41, 035306.	1.3	22
156	Structure and migration of (112) step on (111) twin boundaries in nanocrystalline copper. Journal of Applied Physics, 2008, 104, .	1.1	57
157	High Aspect Ratio Vertical Through-Vias for 3D MEMS Packaging Applications by Optimized Three-Step Deep RIE. Journal of the Electrochemical Society, 2008, 155, H85.	1.3	38
158	A Ruthenium-Based Multimetal-Contact RF MEMS Switch With a Corrugated Diaphragm. Journal of Microelectromechanical Systems, 2008, 17, 1447-1459.	1.7	64
159	A novel method of growing aligned carbon nanotubes at low temperature by using integrated micro-heater. , 2008, , .		0
160	A study on the viscous damping effect for diaphragm-based acoustic MEMS applications. Journal of Micromechanics and Microengineering, 2007, 17, 2253-2263.	1.5	26
161	Aligned carbon nanotubes for through-wafer interconnects. Applied Physics Letters, 2007, 91, .	1.5	74
162	Concept and Analytical analysis of Silicon micro/nanopillars based 3-D stacked microchannel heat sink for advanced heat dissipation applications. , 2007, , .		2

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163	Through-wafer electroplated copper interconnect with ultrafine grains and high density of nanotwins. Applied Physics Letters, 2007, 90, 033111.	1.5	72
164	Deep wet etching-through 1mm pyrex glass wafer for microfluidic applications. , 2007, , .		3
165	Transmission Line Characteristics of a CNT-based Vertical Interconnect Scheme. , 2007, , .		1
166	Double exposure time-averaged in-line digital holography. , 2007, , .		0
167	Fabrication and characterization of fine pitch on-chip copper interconnects for advanced wafer level packaging by a high aspect ratio through AZ9260 resist electroplating. Journal of Micromechanics and Microengineering, 2007, 17, 1078-1086.	1.5	72
168	Influence of deep RIE tolerances on comb-drive actuator performance. Journal Physics D: Applied Physics, 2007, 40, 970-976.	1.3	25
169	Mechanical and microstructural characterization of high aspect ratio through-wafer electroplated copper interconnects. Journal of Micromechanics and Microengineering, 2007, 17, 1749-1757.	1.5	43
170	Characterization of Nano-grained High Aspect Ratio Through-wafer Copper Interconnect Column. , 2007, , .		3
171	Study of surface treatment processes for improvement in the wettability of silicon-based materials used in high aspect ratio through-via copper electroplating. Applied Surface Science, 2007, 253, 8637-8646.	3.1	37
172	Dynamic characterization of MEMS diaphragm using time averaged in-line digital holography. Optics Communications, 2007, 280, 285-290.	1.0	43
173	Piezoelectric thick films and their application in MEMS. Journal of the European Ceramic Society, 2007, 27, 3759-3764.	2.8	34
174	Strategies in deep wet etching of Pyrex glass. Sensors and Actuators A: Physical, 2007, 133, 395-400.	2.0	70
175	Deformation analysis in microstructures and micro-devices. Microelectronics Reliability, 2007, 47, 2226-2230.	0.9	10
176	A MEMS Device for Studying the Friction Behavior of Sidewall Surfaces. , 2007, , .		0
177	Mechanical and microstructure characterization of high aspect ratio electroplated through-wafer copper interconnects. , 2006, , .		1
178	Effect of SF6flow rate on the etched surface profile and bottom grass formation in deep reactive ion etching process. Journal of Physics: Conference Series, 2006, 34, 577-582.	0.3	32
179	Microfabricated microneedle with porous tip for drug delivery. Journal of Micromechanics and Microengineering, 2006, 16, 958-964.	1.5	71
180	Enhanced analytical model for micromachined microphones. Journal of Physics: Conference Series, 2006, 34, 847-852.	0.3	1

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181	Micromachined thick film piezoelectric ultrasonic transducer array. Sensors and Actuators A: Physical, 2006, 130-131, 485-490.	2.0	49
182	Measurement of longitudinal piezoelectric coefficient of film with scanning-modulated interferometer. Sensors and Actuators A: Physical, 2006, 128, 327-332.	2.0	10
183	Aspect-Ratio-Dependent Copper Electrodeposition Technique for Very High Aspect-Ratio Through-Hole Plating. Journal of the Electrochemical Society, 2006, 153, G552.	1.3	126
184	Defect-free wet etching through pyrex glass using Cr/Au mask. Microsystem Technologies, 2006, 12, 935-939.	1.2	70
185	Fabrication and characterization of DRIE-micromachined electrostatic microactuators for hard disk drives. Microsystem Technologies, 2006, 13, 11-19.	1.2	14
186	Analytical modeling for bulk-micromachined condenser microphones. Journal of the Acoustical Society of America, 2006, 120, 750-761.	0.5	28
187	Effect of Clamping Ring Materials and Chuck Temperature on the Formation of Silicon Nanograss in Deep RIE. Journal of the Electrochemical Society, 2006, 153, G771.	1.3	15
188	Fabrication of High Aspect Ratio 35â€‚Î¼m Pitch Through-Wafer Copper Interconnects by Electroplating for 3-D Wafer Stacking. Electrochemical and Solid-State Letters, 2006, 9, G305.	2.2	37
189	Wafer-level packaging of pressure sensor using SU8 photoresist. , 2005, , .		5
190	Stress control in masking layers for deep wet micromachining of Pyrex glass. Sensors and Actuators A: Physical, 2005, 117, 286-292.	2.0	56
191	Optimization of an amorphous silicon mask PECVD process for deep wet etching of Pyrex glass. Surface and Coatings Technology, 2005, 192, 43-47.	2.2	35
192	Analysis of highly doping with boron from spin-on diffusing source. Surface and Coatings Technology, 2005, 198, 309-313.	2.2	5
193	Characterization of masking layers for deep wet etching of glass in an improved HF/HCl solution. Surface and Coatings Technology, 2005, 198, 314-318.	2.2	157
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